

Form PTO-1449				ATTY. DOCKET NO. 1691-0177PUS2	APPLICATION NO. NEW		
INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)				APPLICANT Hiroyuki FUKUYAMA et al.			
				FILING DATE March 26, 2004	GROUP		
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	Kind	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
M	US 5,741,724	A	1998-04-21	Ramdani et al.			
	US						
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FOREIGN PATENT DOCUMENTS							
Office	DOCUMENT NUMBER	Kind	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION
M	JP 2-141495	A	1990-05-30	JAPAN			YES Abs
M	JP 2-153897	A	1990-06-13	JAPAN			YES Abs
OTHER DOCUMENTS (Include Name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.)							
M	T. SHIBATA et al., "Characterization of high-quality epitaxial AlN films grown by MOVPE", Mat. Res. Soc. Symp. Proc., Vol. 693, 2002, pp. I9.3.1-I9.3.4, Material Research Society.						
EXAMINER				DATE CONSIDERED	4/19/2005		
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